



Update on tests with passive strucutres on CHESS 2 chip

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Samples



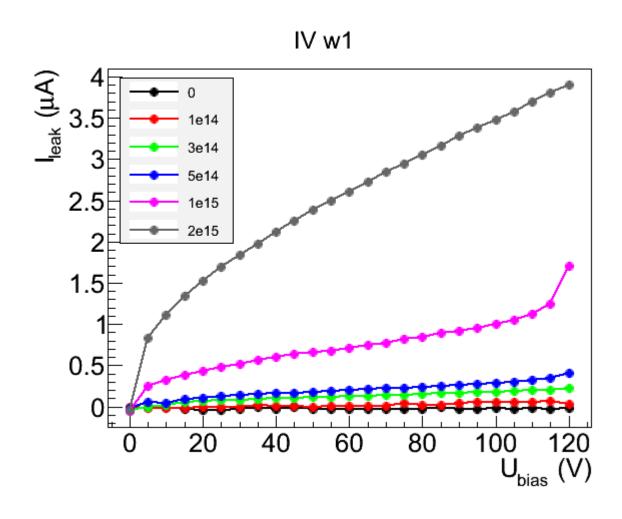
Chips from wafer 1: standard AMS resistivity (20 Ohm-cm)

Resistivity	Wafer	Wafers	Number	
$[\Omega\text{-cm}]$	numbers cut		of cut chips	
std	1-6	1, 2	94	
50-100	7-12	7, 8	97	
200-300	13-18	13, 14	94	
600-2000	19-24	19, 20	95	

Neutron fluences 0e14, 1e14, 3e14, 5e14, 1e15, 2e15 neq/cm2

I-V characteristic

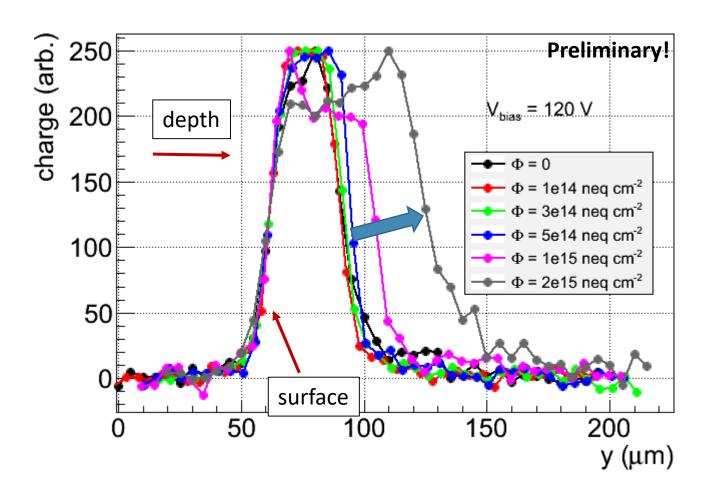




I-V measured on a TCT array (3 x 3 pixels, pixel size 630 x 40 μ m²)

E-TCT Charge collection profiles W1

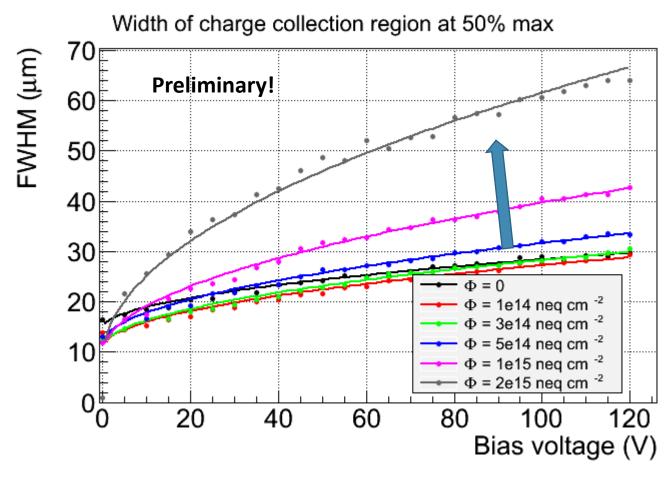




- Moderate charge collection width, but increases with irradiation
- Low resistivity → late acceptor removal

Neff vs. fluence





$$Width(V_{\text{bias}}) = w_0 + \sqrt{\frac{2\varepsilon\varepsilon_0}{e(N_{\text{eff}})}} V_{\text{bias}}$$

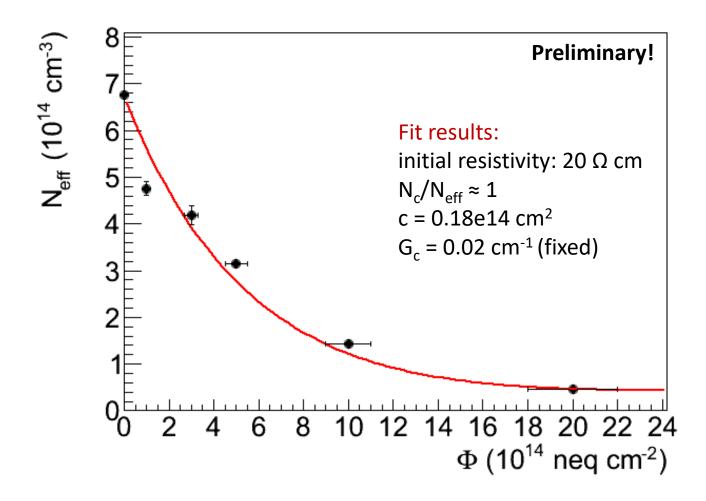
Extract value from fit

N_{eff} vs. fluence



Fit:
$$N_{\text{eff}} = N_{\text{eff0}} - N_{\text{c}} \cdot (1 - \exp(-c \cdot \Phi_{\text{eq}})) + g_{c} \cdot \Phi_{\text{eq}}$$

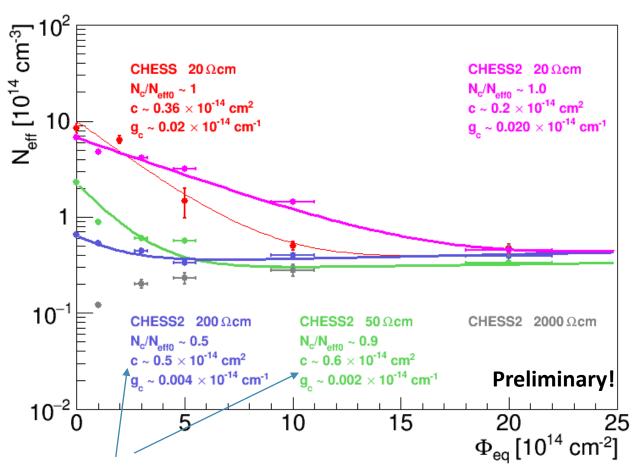
Radiation introduced deep acceptors



Neff vs. fluence



$$\left| N_{\text{eff}} = N_{\text{eff0}} - N_{c} \cdot (1 - \exp(-c \cdot \Phi_{\text{eq}})) + g_{c} \cdot \Phi_{\text{eq}} \right|$$

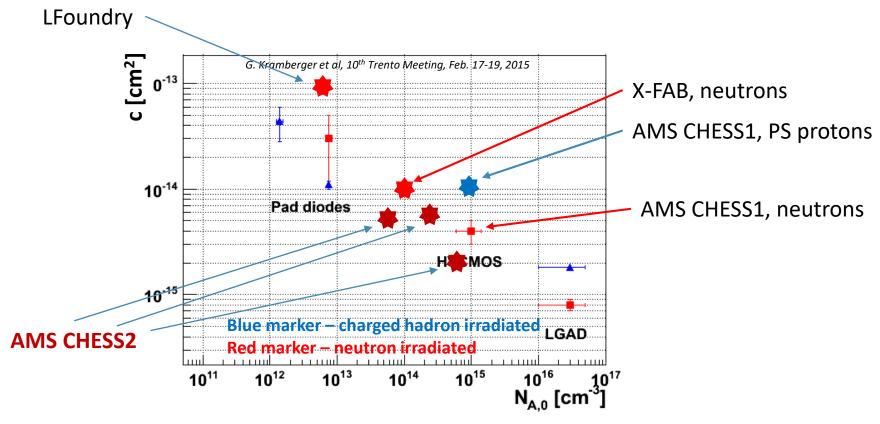


Removal at the highest resistivity substrate is completed below 1e14 neq/cm2 and was not observed in this study

should verify again

Acceptor removal constant vs. doping

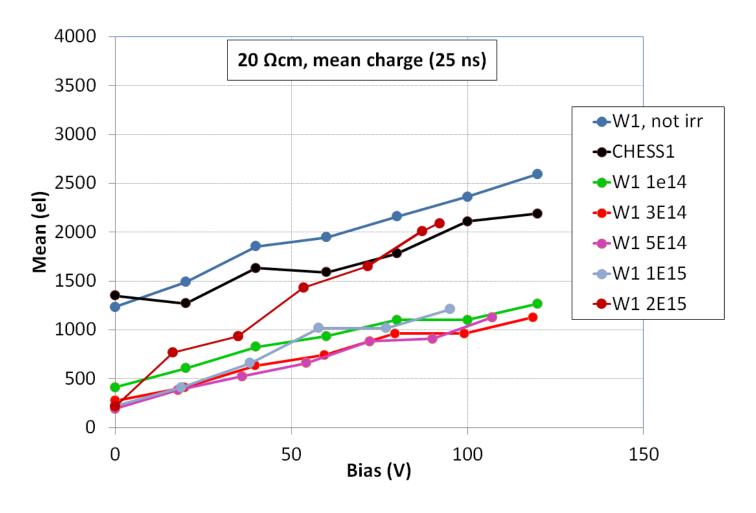




Chip	ρ (Ohmcm)	c (1e-14 cm-2)	Neff/Neff_0	g_c (cm-1)
HV2FEI4	10	0.6	1	0.02 (fixed)
CHESS1	20	0.4	1	0.01
CHESS2	50	0.5	1	0.02 (fixed)
Xfab	100	1	1	0.043
CHESS2	200	0.3	0.8	0.02 (fixed)
LF	2000	10	0.6	0.047

Sr90 measurements

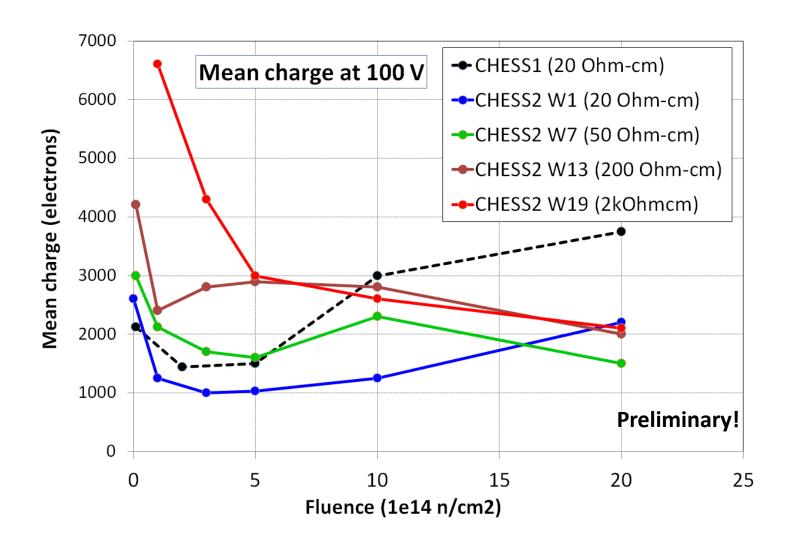




Collected charge is less than expected from E-TCT measurements

Sr90 Comparison for different substrates



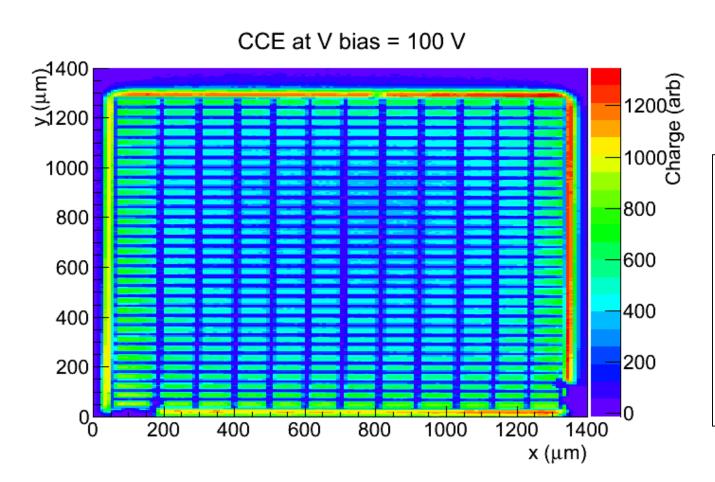


CHESS1 vs. CHESS2: trend is similar, but numbers differ

Top TCT



- Charge from Sr90 measurements systematically only 60 % of that expected for the depletion depth measured by E-TCT
- Investigate with top TCT
 - IR light 980 nm, abs. depth 100 μ m \rightarrow no reflections from back plane



W19 5e14
Big array for Sr90
(1.2 mm x 1.2 mm)

Gaps between pixels due to metalization on top of the chip

But on the large scale intensity in central pixels less than on edges!

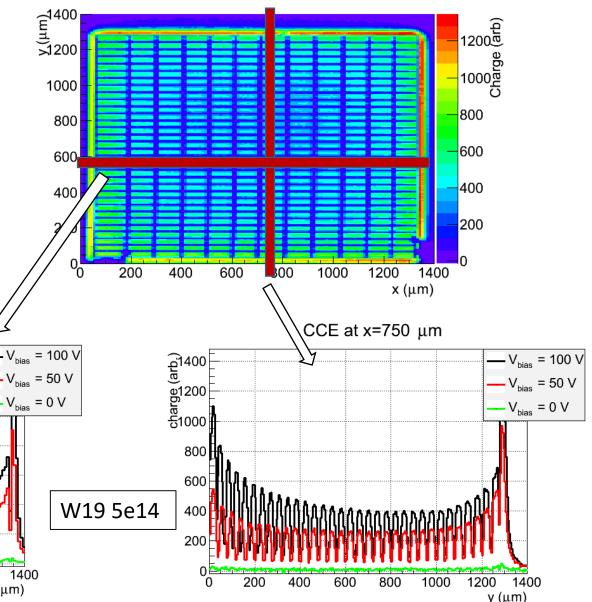
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Top TCT 2



Difference in the collected charge indicates a larger depletion depth on the edges of the Sr 90 array.

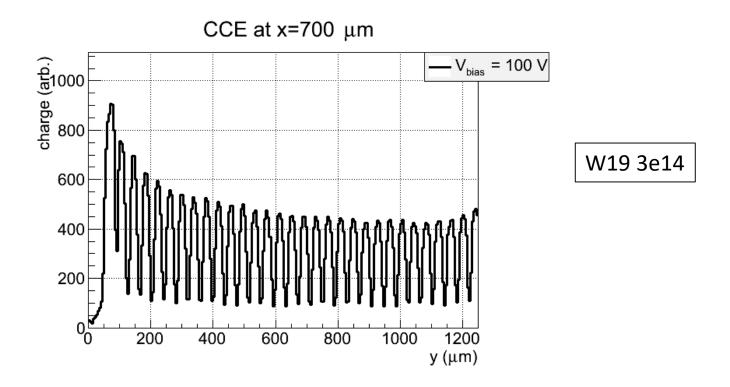
Edge-like pixels also measured in Edge-TCT. This may be a reason for discrepancy between the measurements.



CCE at y=585 µm



Similar behavior observed also on the sample W19 3e14



Summary



- Completed measurements of charge collection on passive structures on CHESS 2
 - 4 wafer resistivities 20 2000 Ohm-cm, each wafer 6 neutron fluences up to 2e15 n/cm2
 - E-TCT and Sr90

• E-TCT:

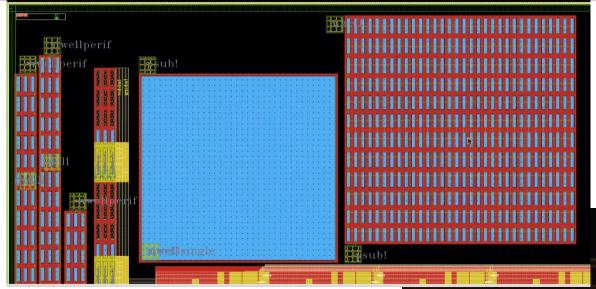
- Behavior of different wafers as expected from previous studies with different substrates
- Acceptor removal plays a role in depleted depth after irradiation effects depending on initial resistivity
- Sr90
 - Collected charge greater at least 1000 electrons for any substrate and fluence
- Systematic discrepancy between E-TCT and Sr90 in collected vs. expected charge charge (40 %)
 - Indications that pixels in a large array collect less charge than pixels with only few neighbors
- Outlook: Tests with active analog structures



BACKUP

Passive structures on CHESS2

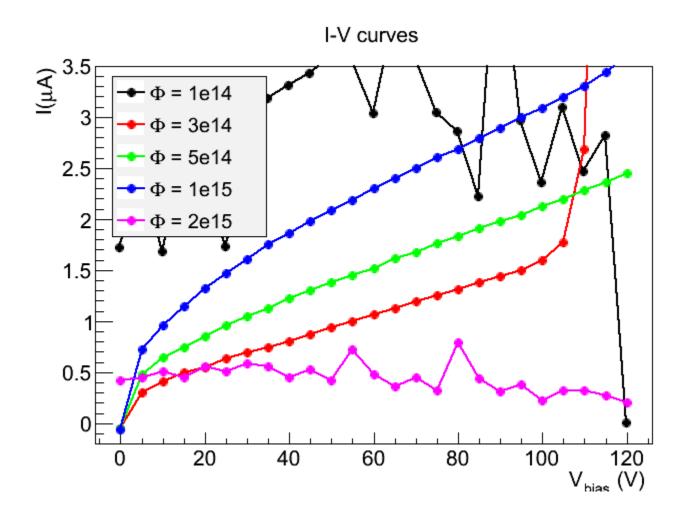




Red traces - metalization



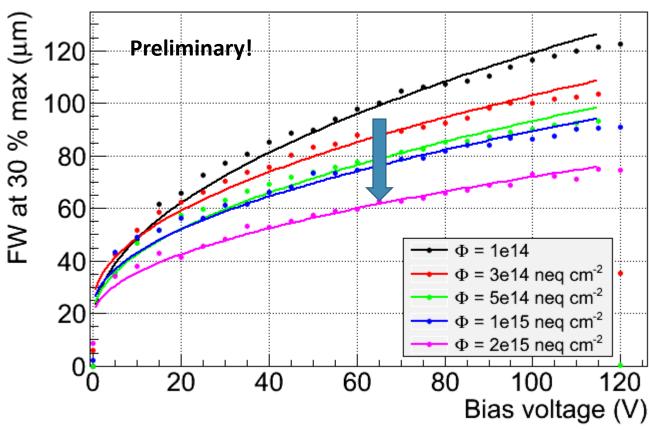




Depletion depth W19







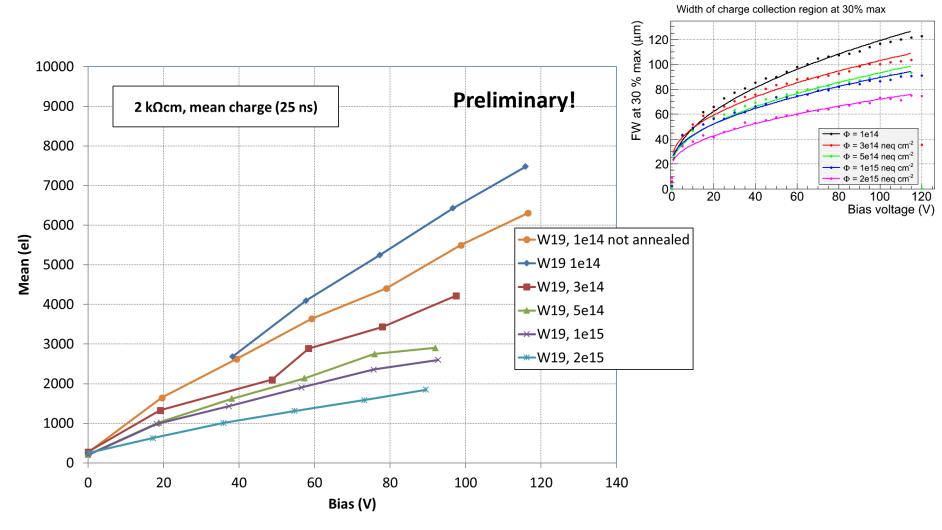
$$Width(V_{\text{bias}}) = w_0 + \sqrt{\frac{2\varepsilon\varepsilon_0}{e_0 N_{\text{eff}}}} V_{\text{bias}}$$

 Sqrt functions falling monotonously with fluence

Sr90 charge



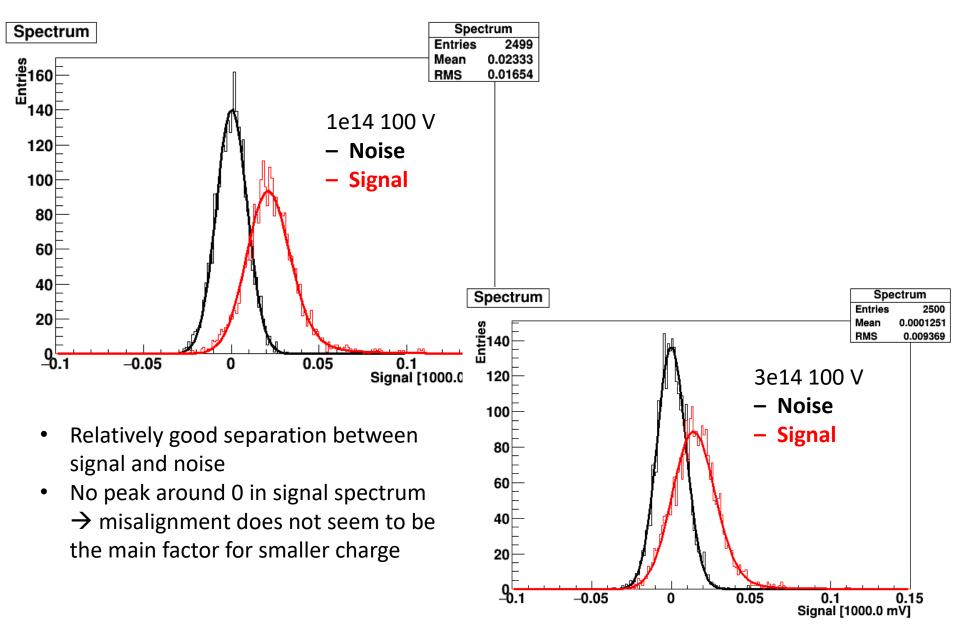
19



- TCT 1e14: depletion zone 120 um at 100 V
- We still collect less charge than expected (f.e. meas. 7000 e vs. 12000 e expected)
- Investigate with top TCT ?

Sr90 spectra W19





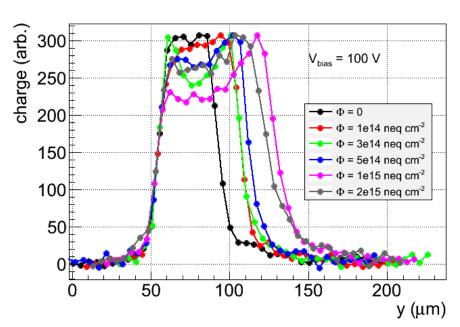
Charge profiles W7, W13



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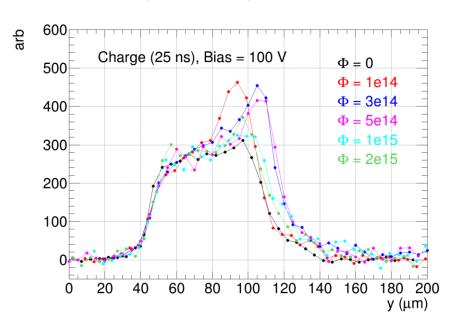
• Edge-TCT charge collection profile across central pixel





• increase of width with fluence up to 1e15

W13 (200 Ω ·cm)



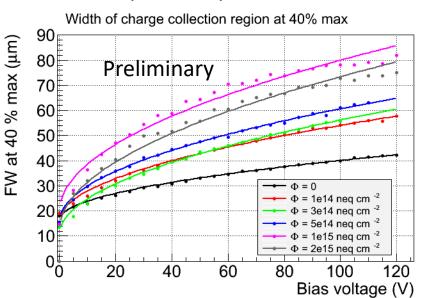
not much change of profile width with fluence

REMINDER Depletion depth W7, W13

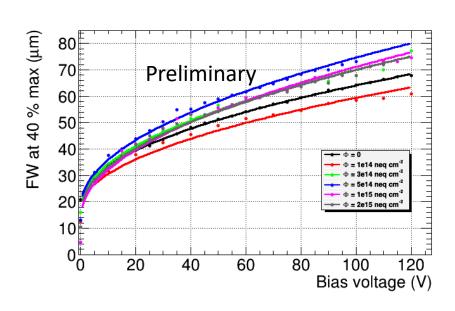


width of charge collection profile vs. bias

W7 (50 Ω ·cm)



W13 (200 Ω ·cm)



Fit:
$$Width(V_{\text{bias}}) = w_0 + \sqrt{\frac{2\varepsilon\varepsilon_0}{e_0 N_{\text{eff}}} V_{\text{bias}}}$$

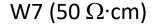
At $\Phi = 0$

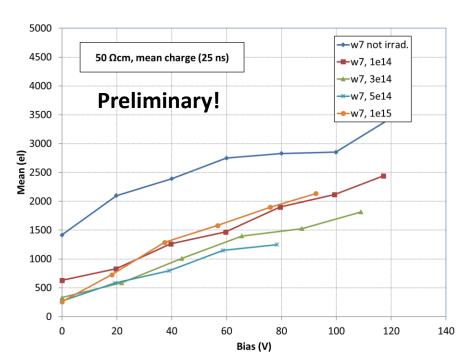
- W7: $N_{eff} = 2.3e14 \text{ cm}^{-3}$ \rightarrow 56 $\Omega \cdot \text{cm}$
- W13: $N_{eff} = 6.6e13 \text{ cm}^{-3}$
- **→** 200 Ω·cm

→ Good fit, good agreement with nominal resistivity

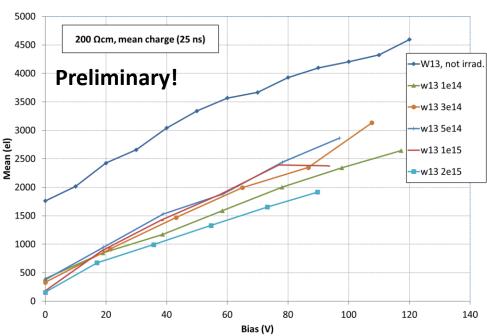
REMINDER Sr90 W7, W13







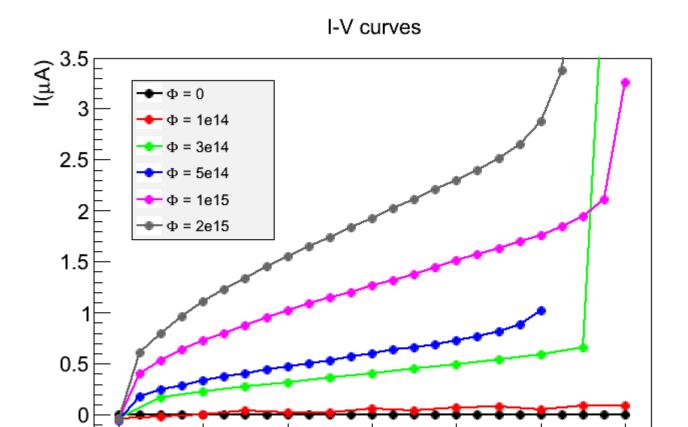
W13 (200 Ω ·cm)



- large drop of collected charge (delta ≈ 1300 el) after first irradiation step to 1e14 n/cm2
 - → reduced contribution from diffusion
- TCT measurements indicate depleted region > 50 μm
 - Expect > 5000 el. from drift
 - Measure 2000 el.

IV-curves wafer 13





No IV curves for wafer 7 due to a bug, but 0e14, 1e14, 1e15, 2e15 OK up to 120 V 5e14 up to 110 V, 3e14 at least up to 90 V

60

80

100

120

 $V_{\text{bias}}(V)$

40

20

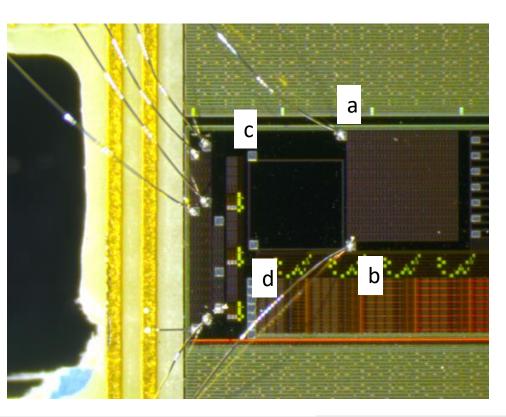
High resistivity wafers



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- After suggestion from Santa Cruz tried biasing the substrate from other pads:
 - a & d → breakdown at 18 V
 - a & b → breakdown at 18 V
 - c & d → breakdown at 1 V
 - c & b → breakdown at 1 V

Planning also to measure IV of irradiated devices on probe station to see if there is improvement after irradiation



a – LPA nwells

b – LPA substrate

c – Large Pad

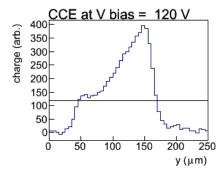
nwells

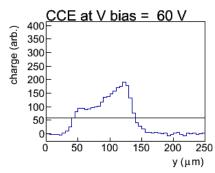
d – Large Pad

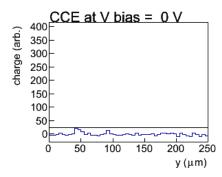
substrate

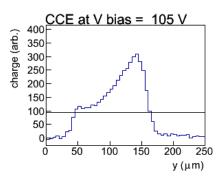
Profiles W19 1e14

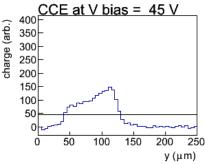


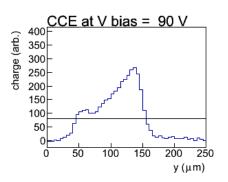


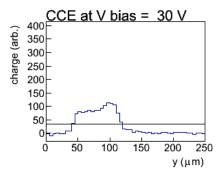


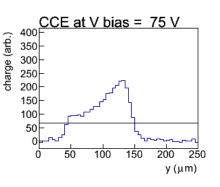


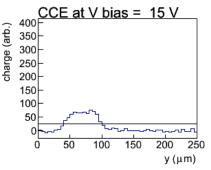






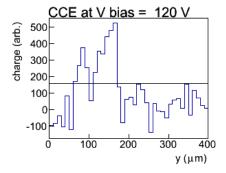


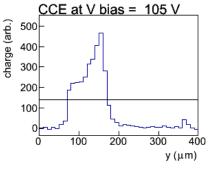


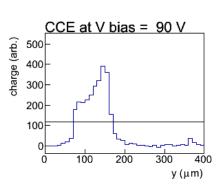


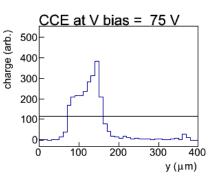
Profiles W19 3e14

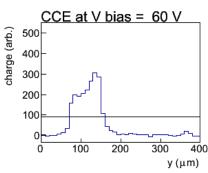


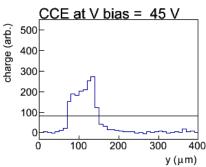


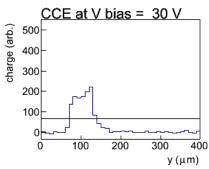


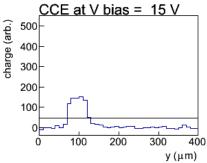


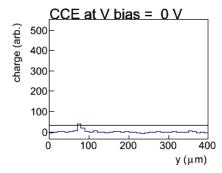






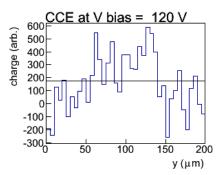


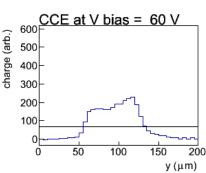


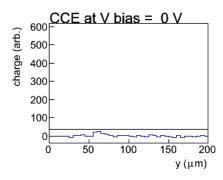


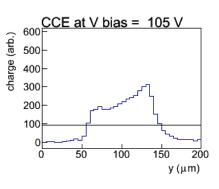
Profiles W19 5e14

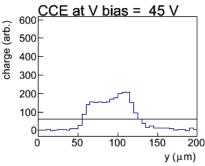


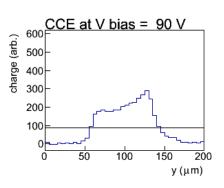


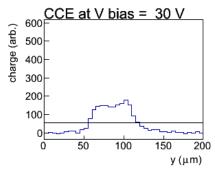


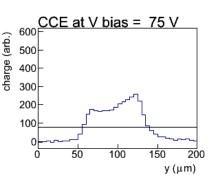


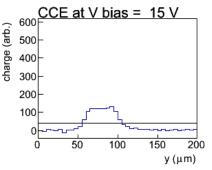






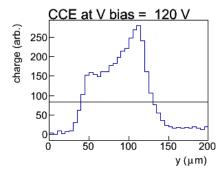


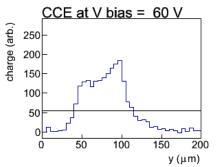


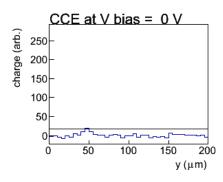


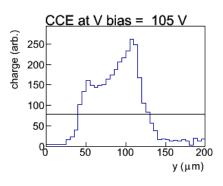
Profiles W19 1e15

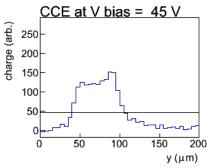


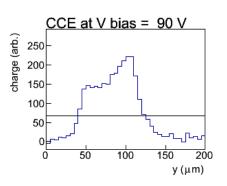


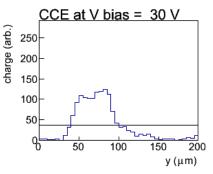


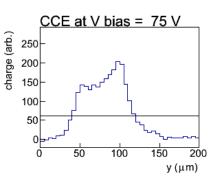


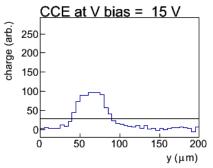












Profiles W19 2e15



